

Amendments to the Specification:

Please replace the paragraph beginning at line 11 on page 1 with the following replacement paragraph:

Typically the wafer to be tested is loaded into the tester securing it to a movable chuck. During the testing process, the chuck moves the wafer into electrical contact with the probe card. This contact occurs between a plurality of electrical contacts on the probe card, typically in the form of ~~microsprings~~ spring contacts, and plurality of discrete connection pads (bond pads) on the dies. Several different types of electrical contacts are known and used on probe cards, including without limitation needle contacts, cobra-style contacts, spring contacts, and the like. In this manner, the semiconductor dies can be tested and exercised, prior to singulating the dies from the wafer.